

FORM PTO-1449 (Modified)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY.DOCKET NO. 06029 USA	SERIAL NO. 09/641,933 PTO
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)		APPLICANT Pearlstein, et al.	FILING DATE August 18, 2000
		FILING DATE August 18, 2000	
(37 CFR 1.98(b))		GROUP 3753	

JC854 U.S. PTO  
09/641,933  
09/18/00

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
GW		5	9	3	7	8	9	5	8/17/99	LeFebre, et al	137	494	4/17/98
		6	0	4	5	1	1	5	4/4/00	Martin, Jr., et al	251	118	4/17/98
		4	7	4	4	2	2	1	5/17/88	Karl O. Knollmueller	62	48	6/29/87
		5	5	1	8	5	2	8	5/21/96	Tom, et al	95	103	10/13/94
		5	7	0	4	9	6	5	1/6/98	Tom et al	95	95	5/20/96
		5	7	0	4	9	6	7	1/6/98	Tom, et al	96	143	5/20/96
		5	7	0	7	4	2	4	1/13/98	Tom, et al	95	95	11/1/96
		5	4	0	9	5	2	6	4/25/95	Zheng, et al	96	132	10/5/93
		6	0	2	7	5	4	7	2/22/00	Tom, et al	95	96	5/18/98
GW		6	0	8	9	0	2	7	7/18/00	Wang, et al	62	46.1	4/28/99

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION		
														YES	NO
GW		9	9	0	9	1	3	7	2/25/99	WO	C12M	3/00		X	
		0	9	1	6	8	9	1	5/19/99	EP	F17C	13/04		X	
GW		0	9	1	6	8	9	1	8/9/99	EP	F17C	13/04		X	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

GW		"A New Era In Gas Handling Safety: Sub-Atmospheric..." McManus, JV, et al, Semiconductor Fabtech.
		"Sub-Atmospheric Pressure Gas Delivery System For Chemical." Donatucci, et al, IBM Microelectronics Div.
GW		"Reducing the HPM Risk: Pressure-actuated Gas Delivery", Olander, et al, Semiconductor Fabtech.

EXAMINER George Walton DATE CONSIDERED 9/29/01

EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

J. Klein  
#4  
4/11/2001